



ABSTRACT OF THE DISCLOSURE

A focused charged particle beam device has a charged particle source, a focusing lens system for focusing a charged particle beam emitted from the charged particle source, a sample stage for supporting a sample, a movement mechanism for movement of the sample stage along three axes and a tilting mechanism for tilting movement of the sample stage about two of the three axes so that rotation of the sample stage is unnecessary. In a preferred embodiment, the tilting mechanism is mounted below the movement mechanism and a point at which the two axes of the tilting mechanism cross is aligned with an optical axis of the focusing lens system.